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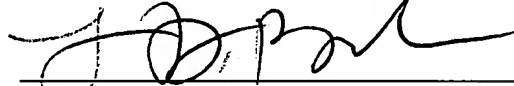
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PATENT
RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 1765

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Lisa D. Bronk

Appl No. : 10/090,915 Confirmation No. 7688
Applicant : Konstantin Holdermann
Filed : March 5, 2002
Title : ETCHING SOLUTION FOR WET CHEMICAL PYRAMIDAL TEXTURE
ETCHING OF SILICON SURFACES

TC/A.U. : 1765
Examiner : Shamim Ahmed

Docket No. : 47585/RAG/S969

Customer No. : 23363

RESPONSE AFTER FINAL ACTION

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Post Office Box 7068
Pasadena, CA 91109-7068
August 3, 2004

Commissioner:

In response to the Office action of May 4, 2004, please consider the following remarks.

REMARKS/ARGUMENTS

As a preliminary matter, applicant would like to thank the Examiner for taking the time to conduct a telephonic interview with applicant's representative on July 14, 2004. During that interview, the Bailey (U.S. Patent No. 4,137,123) and Uchimura (U.S. Patent No. 5,165,957) references were discussed, as well